

HW10 solution

MTLE-6120: Spring 2018

Due: Apr 23, 2018

1. Kasap 5.29: Seebeck coefficient and thermal drift in semiconductor devices

- (a) Holes and electrons both diffuse from hot to cold sides, but correspond to opposite charge transport directions. Electrons lead to negative S in n -type semiconductors, compared to holes which yield positive S in p -type semiconductor.
- (b) Charge neutrality for an n -type semiconductor yields $N_c \exp \frac{E_F - E_c}{k_B T} = N_d$. Therefore the Seebeck coefficient is:

$$S_n = -\frac{k_B}{e} \left[2 + \frac{E_c - E_F}{k_B T} \right] = -\frac{k_B}{e} \left[2 + \ln \frac{N_c}{N_d} \right]$$

Given that $k_B/e = 8.63 \times 10^{-5}$ V/K and $N_c = 2.8 \times 10^{19}$ cm⁻³, we can easily calculate $S_n = -1.26 \times 10^{-3}$ V/K for $N_d = 10^{14}$ cm⁻³ and -8.58×10^{-4} for $N_d = 10^{16}$ cm⁻³. The implication for devices is that temperature changes and gradients can induce changes in the voltages at the outputs of devices, thereby contributing to thermal drift.

- (c) We have already calculated $S_n = -1.26 \times 10^{-3}$ V/K for $N_d = 10^{14}$ cm⁻³ n -type Si. We can neglect S_p because with this asymmetric doping, most of the potential drop is in the n side. The potential corresponding to 1C i.e. 1K change of temperature is 1.26 mV, which amplified by a gain of 100 will produce an output of 0.13 V.

2. Kasap 6.2: The Si pn junction (estimating recombination and diffusion currents)

In answering, ‘what is your conclusion’, include your expectation for the diode ideality factor η .

Hint: you will need the diffusion constants for the carriers. Assume $D_e = 34.9$ cm²/s and $D_h = 11.6$ cm²/s. (Diffusion constants are related to mobilities by the Einstein relation $D_{e/h} = (k_B T/e)\mu_{e/h}$) Besides that, the only other Si -specific properties you should need are $n_i = 10^{10}$ cm⁻³ and $\epsilon_r = 11.7$.

The diffusion current is $j_s = j_{s0} \exp \frac{eV}{k_B T}$ where

$$j_{s0} = en_i^2 \left[\frac{D_h}{L_h N_d} + \frac{D_e}{L_e N_a} \right] = en_i^2 \left[\frac{1}{\sqrt{D_h \tau_h} N_d} + \frac{1}{\sqrt{D_e \tau_e} N_a} \right]$$

while the recombination current is $j_r = j_{r0} \exp \frac{eV}{2k_B T}$ where

$$j_{r0} = \frac{en_i}{2} \left[\frac{w_p}{\tau_e} + \frac{w_n}{\tau_h} \right].$$

Note that for this we first need to calculate the built-in potential

$$V_0 = k_B T \log \frac{N_a N_d}{n_i^2},$$

the depletion width

$$w_0 = \sqrt{\frac{2\epsilon(N_a + N_d)(V_0 - V)}{eN_a N_d}}$$

and from that the widths on the two sides w_p and w_n .

- (a) Let us start with the recombination times. Using the given formula, $\tau_e = 2.4 \times 10^{-8}$ s in the p -region (irrelevant) and $\tau_h = 4.9 \times 10^{-7}$ s in the n -region (required).

The built in potential evaluates to $V_0 = 0.77$ V, which yields a depletion width of $w_0 = 4.74 \times 10^{-5}$ cm (474 nm). This splits into $w_p = 4.74 \times 10^{-8}$ cm (0.47 nm, irrelevant) and $w_n \approx w_0 = 4.73 \times 10^{-5}$ cm (473 nm, required).

From these, we can calculate the prefactors for the two current contributions as $j_s0 = 6.74 \times 10^{-12}$ A/cm² and $j_{r0} = 1.58 \times 10^{-7}$ A/cm². Finally accounting for the area of $1 \text{ mm}^2 = 0.01 \text{ cm}^2$ and the exponential factors, we get

$$I_s = 0.82 \text{ mA} \quad \text{and} \quad I_r = 0.17 \text{ mA}$$

Therefore recombination is comparable but smaller than the diffusion contribution, which will yield an ideality coefficient closer to 1.

- (b) The recombination times are, $\tau_e = \tau_h = 2.4 \times 10^{-8}$ s on both sides of the interface.

The built in potential evaluates to $V_0 = 0.95$ V, which yields a depletion width of $w_0 = 3.02 \times 10^{-6}$ cm (30 nm). This splits evenly into $w_p = w_n = 1.51 \times 10^{-6}$ cm (15 nm).

From these, we can calculate the prefactors for the two current contributions as $j_s0 = 4.80 \times 10^{-14}$ A/cm² and $j_{r0} = 2.03 \times 10^{-7}$ A/cm². Finally accounting for the area of $1 \text{ mm}^2 = 0.01 \text{ cm}^2$ and the exponential factors, we get

$$I_s = 5.8 \text{ } \mu\text{A} \quad \text{and} \quad I_r = 0.22 \text{ mA}$$

Therefore recombination far exceeds the diffusion contribution, which will yield an ideality factor closer to 2.

3. Kasap 6.15: Ultimate limits to device performance (of an n -channel FET)

Note: for part (c), assume and justify reasonable values for the barriers. Consider tunneling to become important when tunneling probabilities $\sim 10^{-6}$.

Also, there might be a typo in the example number referenced by some editions of the book. (In mine, it says 3.10, but it should be 3.12.)

- (a) The electron PE changes by $eV_{DS} \geq k_B T \approx 0.026$ eV, in order to exceed thermal fluctuations. Therefore $V_{DS} \geq 0.026$ V.

Given a field of 10^6 V/m, this V_{DS} corresponds to a channel length $L \sim 2.6 \times 10^{-8}$ m (26 nm).

With saturated velocity of 10^5 m/s, this corresponds to a transit time of $\tau_t \sim 2.6 \times 10^{-13}$ s (0.26 ps).

- (b) The characteristic time associated with $eV_{DS} \sim k_B T \approx 0.026$ eV is $\tau \sim \hbar / (k_B T) \sim 2.5 \times 10^{-14}$ s (25 fs), an order of magnitude smaller than the transit time above.

- (c) We can assume that the barriers for tunneling are ~ 1 eV. This is the typical magnitude for built-in potentials in Si, which affects the barrier for tunneling across the channel. This typical band offsets between Si and SiO₂ are also in the same order of magnitude, with ~ 3 eV barrier for electrons and ~ 2 eV barriers for holes.

The tunneling probability is $T \sim \exp(-2L\sqrt{2m(V-E)}/\hbar)$. For barrier $(V-E) \sim 1$ eV, the wavevector $\kappa = \sqrt{2m(V-E)}/\hbar \sim 5 \times 10^9 \text{ m}^{-1}$. Therefore for $\exp(-2L\kappa) \sim 10^{-6}$, $L \sim 1.4$ nm. At these channel lengths or oxide thicknesses, tunneling will become a limitation.